



## TUMA2 2D Scanner for Surface-Wise Measurements of Complex Permittivity of Emerging LTCC and ULTCC Materials

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# LTCC/ULTCC vs HTCC



- Lowered sintering temperature (compared to HTCC) keeping compatibility with existing fabrication methods
- Lowered energy consumption
- Lower production costs
- Environmental friendliness
- Application to demanding 5G and 6G systems
  - Telecommunication
  - Computer industry
  - Automotive industry







- Precise measurements of complex permittivity
- Point-wise measurements typical
  - resonant methods are proven to be the most accurate
- Surface-wise testing ?

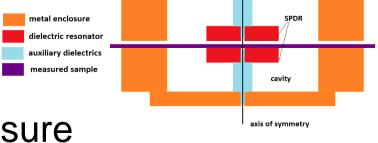
- 2D maps of dielectric constant and loss tangent across material surface
- Important for high component packaging on single substrate

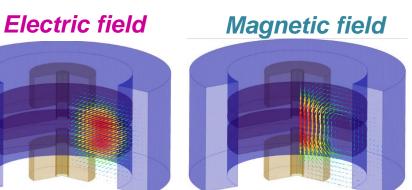


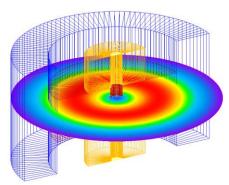
# SPDR fixtures for materials testing



- Split-Post Dielectric Resonators (SPDRs)
- H-field is only vertical at the side wall of the enclosure
- E-field tangential to SUT
- Easy SUT insertion through slot
- Field patterns remain practically unchanged



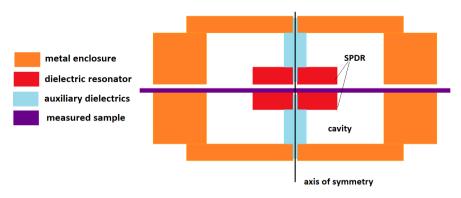






## SPDR fixtures for materials testing





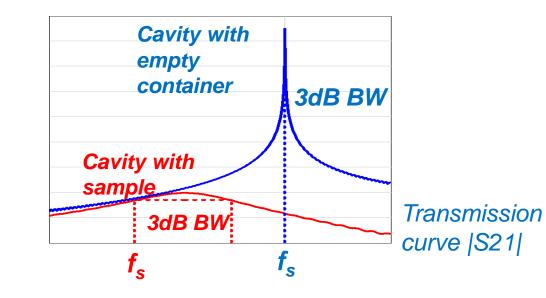
Non-destructive measurement

 Resonant frequencies and Q-factors change, upon SUT insertion

SUT of  $\varepsilon_s = \varepsilon_s' - j \varepsilon_s''$  is inserted into DR:

resonant frequency changes from  $f_e$  to  $f_s$ 

and Q-factor changes from  $Q_e$  to  $Q_s$ .



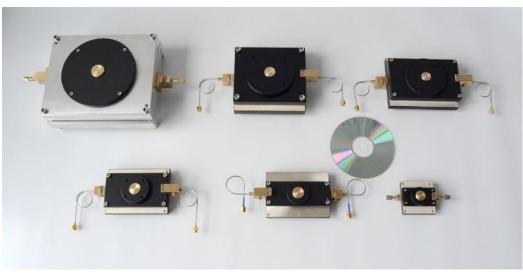


## Point-wise measurement with SPDR

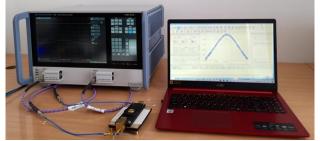


#### Measurement setups

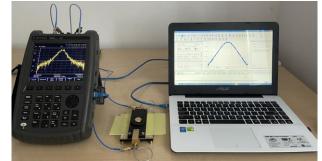
#### Family of SPDR test-fixtures



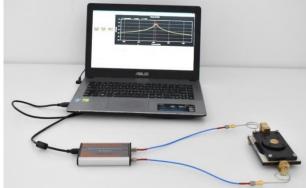
#### **Devices covering 1 – 15 GHz**



#### Laboratory-scale VNA



#### Hand-held VNA



Portable Microwave Q-Meter



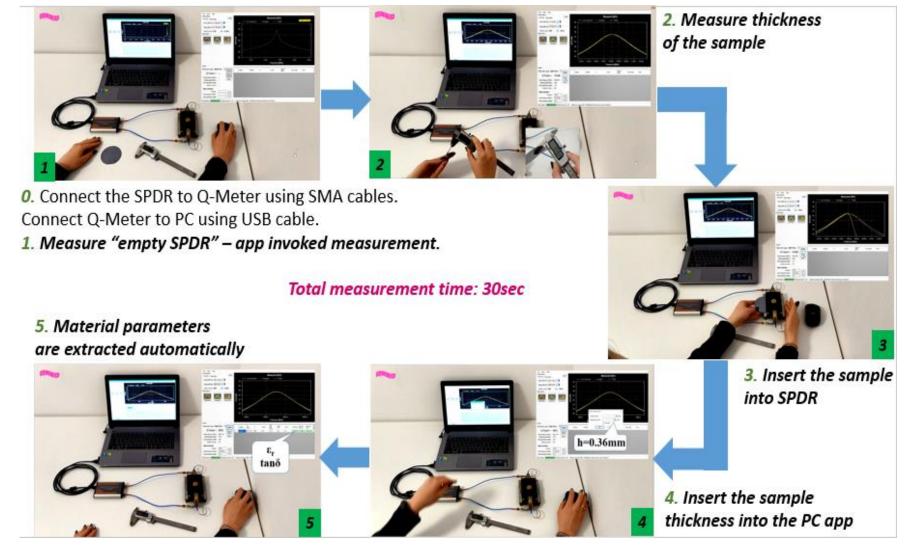




## Point-wise measurement with SPDR



**Operation workflow – with the use of Q-Meter** 



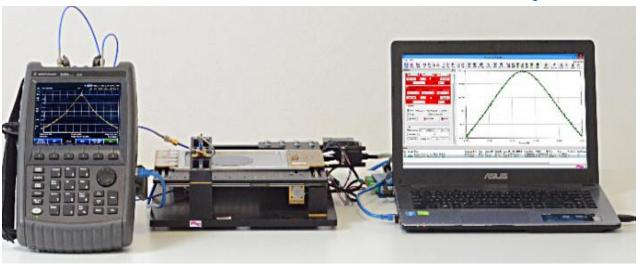




## Surface-wise measurements



- Microwave measurement performed over a grid of points across SUT surface
- Extracted parameters' values aggregated into 2D maps of Dk, Df, and resistivity
- 2D SPDR scanner operating at 10GHz
- SUT placed on a Teflon foil (stable and intact)
- Positioning and measurement controlled and invoked with dedicated Master Unit Control Application (PC app)



#### 2D SPDR scanner measurement setup



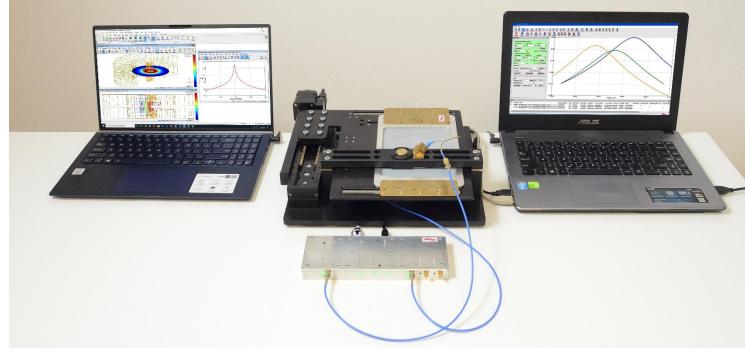


## Surface-wise measurements (2)



#### Portable 2D SPDR scanner measurement setup

- Fast measurements required
- Microwave Q-Meter
  - Low-cost replacement for VNA
  - Portable







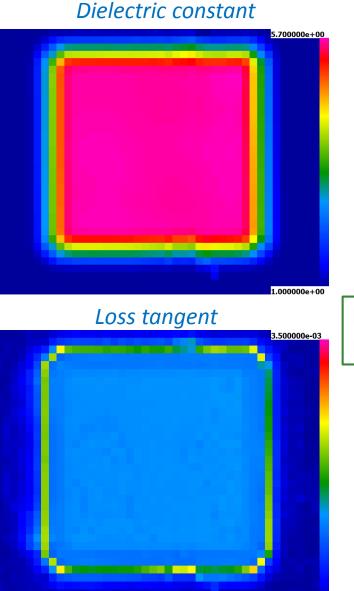
## LTCC materials



## Commercial Ferro A6M substrate (50x50mm)



WAVE THEORY &



#### 2D surface imaging with SPDR 10GHz scanner

Scanning range:	85 x 70 mm
Scanning step:	2 mm
Number of meas. Points:	1548
Scanning time:	ca. 2 hour

Dielectric constant variation:ca. 5.56 - 5.68Loss tangent variation:ca. 0.00101 - 0.00118

Uncertainty due to thickness variation –  $\pm 1\%$ 

0.000000e+00

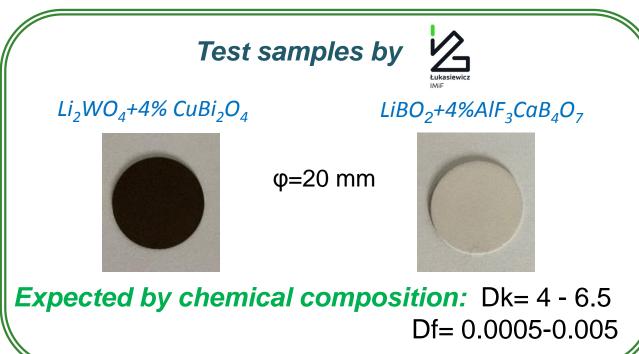


## **ULTCC** materials



### **ULTCC** material fabrication scheme

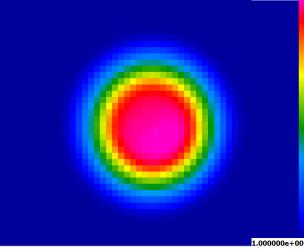
- Material fabrication procedure:
  - solid state synthesis of oxide components,
  - ball milling,
  - uniaxial pressing of pellets.
- Sintering at 610-650° C for 1 2h.



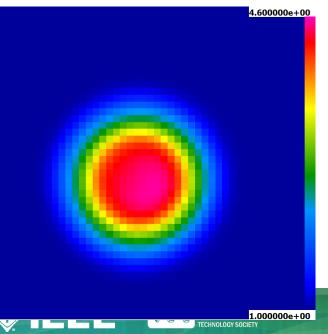




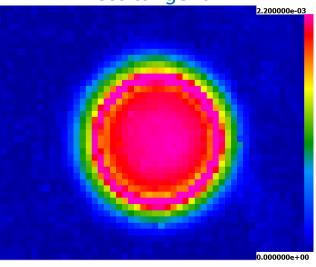
#### Dielectric constant



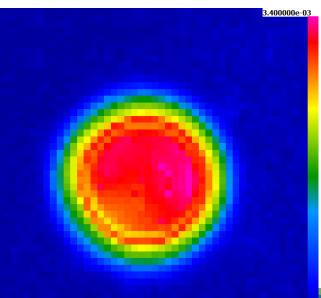
Dielectric constant



# ULTCC testing (1)



#### Loss tangent



0.00000000+00

Scanning range:	
Scanning step:	
Number of meas. Points:	
Scanning time:	

50 x 40 mm 1 mm 2091 ca. 2.5 hour

Dielectric constant variation:ca. 5 - 5.5Loss tangent variation:ca. 0.00202 - 0.00219

Uncertainty due to thickness variation  $-\pm 2.5\%$ 

Scanning range:	50 x 55 mm
Scanning step:	1 mm
Number of meas. Points:	2856
Scanning time:	ca. 3.5 hour

Dielectric constant variation:ca. 4.25 - 4.53Loss tangent variation:ca. 0.003 - 0.00339

Uncertainty due to thickness variation  $-\pm3\%$ 





## ULTCC materials (2)

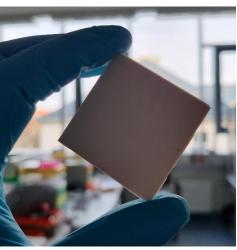
### **ULTCC** tapes to substrates (ULTCC40)

- Fabrication procedures:
  - Solid state mixing of raw materials (Al<sub>2</sub>O<sub>3</sub>, SiO<sub>2</sub> Bi based glass powders)
  - Tape casting
  - Multilayer lamination
  - Binderburnout and sintering
  - Sintering at 650°C/30min

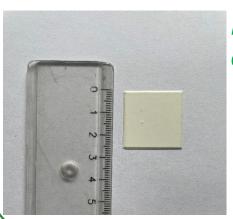
#### *Test samples by Fraunhofer*







50 x 50 x 0.5 mm



# Expected by chemical composition:

Dk= 10 Df= 0.002 at 10 GHz TCDk ~ 600-750 ppm/K

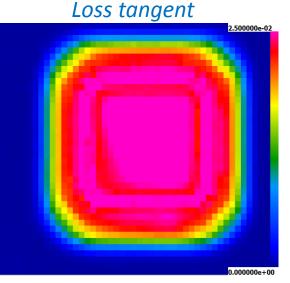




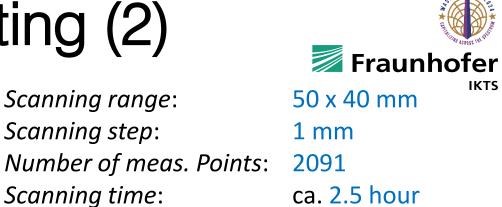


## ULTCC testing (2)

# Diedectric constant



#### Dielectric constant Loonone+0 Dielectric constant Loonone+0 Dielectric constant Loonone+0 Dielectric constant Dielectric constan



Dielectric constant variation:ca. 9.6 - 9.99Loss tangent variation:ca. 0.022 - 0.0275

Uncertainty due to thickness variation  $-\pm 2\%$ 

Scanning range:	50 x 55 mm
Scanning step:	1 mm
Number of meas. Points:	2856
Scanning time:	ca. 3.5 hour

Dielectric constant variation: ca. 10.02 – 10.13 Loss tangent variation: ca. 0.028 – 0.038

Uncertainty due to thickness variation –  $\pm 0.5\%$ 





0.000000e+00



## ULTCC testing (3)



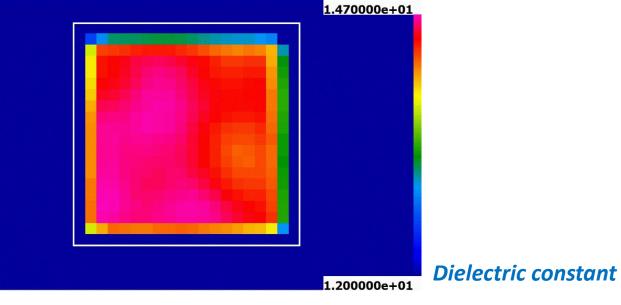
#### **ULTCC Sample 3**

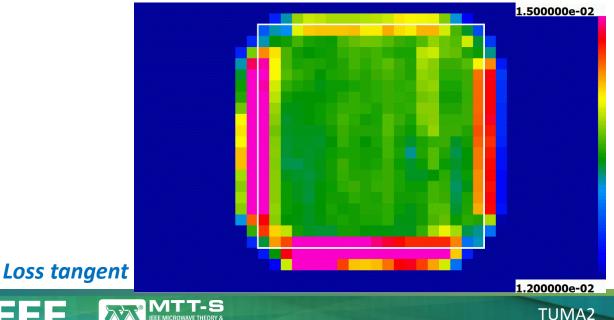
Scanning range:	80 x 50 mm
Scanning step:	2 mm
Number of meas. Points:	1001
Scanning time:	ca. 1 hour

Dielectric constant variation:ca. 14.7 – 14Loss tangent variation:ca. 0.0135 ±0.002

Uncertainty due to thickness variation  $-\pm 2\%$ 

\* M. Olszewska-Placha et al. "Bulk glass-ceramic composites and ULTCC substrates for microwave and millimetre-wave applications", Materials Research Bulletin, April 2024



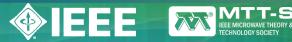




Summary



- Quantitative and qualitative measures of uniformity of dielectric properties
- Material quality testing
- Detection of defects
- Repeatability of technological fabrication process
- Important for increasing density of electronic components over single substrate





## Acknowledgement











# Visit



## Booth #2245



